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Confirmation No. 5700

In re Patent Application of

New York, New York

Katsuhiko MIYA et al.

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Examiner: ---

For: SUBSTRATE PROCESSING APPARATUSVIA EFS-WEB

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

SUBMISSION

Sir:

Submitted herewith is copies of Japanese references together with a form listing the same for the convenience of the Examiner. Also included is a Japanese Office Action which cites the attached art.

I certify that each item of information contained in this Submission was cited in a communication from a foreign patent office in a counterpart foreign application not more than 3 months prior to the filing of this Submission. I certify that each item of information contained in this Submission was cited in a communication from a foreign patent office in a counterpart foreign application not more than 3 months prior to the filing of this Submission.

No fee is believed to be due with this submission, since it is being made prior to issuance of a first Office Action concerning this matter. If any fee is due, however, authorization is hereby provided to charge the required amount to Deposit Account No. 15-0700.

Respectfully submitted,

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ON November 18, 2008



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